



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Tsutomu Saimoto et al.

Application No.: 10/506,806

Filed: September 7, 2004

For: PRESSURE SENSITIVE ADHESIVE
FILM FOR PROTECTION OF
SEMICONDUCTOR WAFER
SURFACE AND METHOD OF
PROTECTING SEMICONDUCTOR
WAFER WITH THE PRESSURE
SENSITIVE ADHESIVE FILM

) **MAIL STOP AMENDMENT**
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) Group Art Unit: 2811
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) Examiner: Thomas J. Magee
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) Confirmation No.: 5415
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**AMENDMENT AND SUBMISSION OF VERIFIED TRANSLATION OF
PRIORITY APPLICATION**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed June 2, 2005, please amend the
above-identified application as follows: